

PATENT ABSTRACTS OF JAPAN

(11) Publication number: **2002357541 A**

(43) Date of publication of application: **13.12.02**

(51) Int. Cl.
G01N 21/27
G01M 11/00
G01N 21/94
G03G 21/00
G03G 21/16

(21) Application number: **2001164206**

(71) Applicant: **RICOH CO LTD**

(22) Date of filing: **31.05.01**

(72) Inventor: **MIYAUCHI TADANAO**

(54) **CONTAMINATION MONITOR FOR IMAGE FORMING APPARATUS**

(57) Abstract:

PROBLEM TO BE SOLVED: To provide a contamination monitor for an image forming apparatus capable of obtaining information to monitor a contaminating state of a component for forming an image and to clarify a type, a generation source and a generating state of a contaminant.

SOLUTION: The contamination monitor for the image forming apparatus comprises a high refractive index material 2 which has a large refractive index and which is transparent in an infrared region, an infrared ray source 1, a detector 3 and a reflecting mirror 4. The infrared ray IR is passing through the material 2 provided in the image forming apparatus while repeating total reflecting.

COPYRIGHT: (C)2003,JPO

